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| FORM PTO-1449 (Modified) | U.S. Department of Commerce Patent and Trademark Office | 004066/CONS/MBE Attorney Docket No.: | Serial No.: 09/869,966 |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary) | | Applicant: Arackaparambil et al. | |
| (37 CFR § 1.98(b)) | | Filing Date: 07/29/99 | Group: 2788 2121 |

U.S. PATENT DOCUMENTS

| Examiner Initials | | Serial/Patent Number | Issue Date | Applicant/Patentee | Class | Subclass | Filing Date |
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| SND | AB | 5,754,297 | 5/19/98 | Nulman | 356 | 381 | 4/14/97 |
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FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION

| | | Document Number | Publication Date | Country / Patent Office | Class | Subclass | Translation Yes No |
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| SND | AK | R. Zorich, <u>Handbook Of Quality Integrated Circuit Manufacturing</u> , Academic Press Inc., pp. 464-498, 1991. | | | | | |
| SND | AL | SEMI E10-96, <u>Standard For Definition And Measurement Of Equipment Reliability, Availability And Maintainability (RAM)</u> , published by Semiconductor Equipment and Materials International (SEMI), pp. 1-23, 1996 | | | | | |
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Examiner:

Harker

Date Considered:

3/21/02

EXAMINER:

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Sheet 1 of 1

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| FORM PTO-1449 (Modified) | U.S. Department of Commerce Patent and Trademark Office | 004066/CONS/MBE Attorney Docket No.: | Serial No.: 09,363,966 |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary) | | Applicant: Arackaparambil et al. | |
| (37 CFR § 1.98(b)) | | Filing Date: 7/29/99 | Group: 2786 2121 |

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| FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION | | | | | | | | |
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| | | Document Number | Publication Date | Country / Patent Office | Class | Subclass | Translation Yes | No |
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| Examiner: <i>M. S. S.</i> | Date Considered: 3/21/02 |
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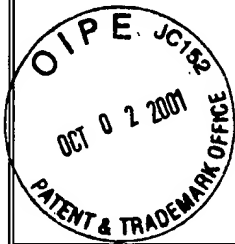
Group: ~~2786~~ 2121

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INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(PTO-1449)


 ATTY. DOCKET NO.
4066/Consilium/MBE

 SERIAL NO.
09/363,966

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OCT 04 2001

 APPLICANT
John F. ARACKAPARAMBIL et al.

Technology Center 2100

 FILING DATE
July 29, 1999

 GROUP
2786 2121

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| EXAMINER'S INITIALS | PATENT NO. | DATE | NAME | CLASS | SUBCLASS | FILING DATE |
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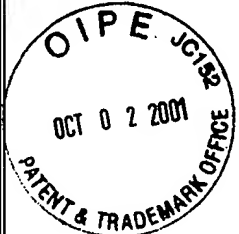
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| INFORMATION DISCLOSURE CITATION IN AN APPLICATION  (PTO-1449) | ATTY. DOCKET NO. 4066/Consilium/MBE | SERIAL NO. 09/363,966 <div style="text-align: center; border: 1px solid black; padding: 5px;"> RECEIVED OCT 04 2001 </div> |
| APPLICANT John F. ARACKAPARAMBIL et al. Technology Center 2100 | | |
| FILING DATE July 29, 1999 | | GROUP 2786 2121 |

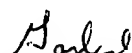
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